

Docket No.: 260055US26SP PCT



ATTORNEYS AT LAW

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

RE: Application Serial No.: 10/509,338
Applicants: Takehiro UEDA, et al.
Filing Date: October 8, 2004
For: METHOD FOR SUPPRESSING CHARGING OF COMPONENT IN
VACUUM PROCESSING CHAMBER OF PLASMA PROCESSOR
AND PLASMA PROCESSOR
Group Art Unit: 1792
Examiner: DAHIMENE, M.

SIR:

Attached hereto for filing are the following papers:

STATEMENT OF SUBSTANCE OF INTERVIEW UNDER MPEP § 713.04

Credit card payment is being made online (if electronically filed), or is attached hereto (if paper filed), in the amount of **\$0.00** to cover any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R. 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. **15-0030**. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.

A handwritten signature in dark ink, appearing to read "Steven P. Weihrouch", is written over a horizontal line.

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